



IFW

Atty. Docket No.: NTI-849

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Linyong Pang

Application No.: 10/785,254

Group No.: 2825

Filing Date: February 23, 2004

Examiner: Sun J. Lin

For: "Method And Apparatus Of Wafer Print Simulation Using Hybrid Model
With Mask Optical Images"

Date: April 13, 2005

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

STATUS INQUIRY

1. More than twelve months have passed since the filing of this application on February 23, 2004. No communication has been received from the Patent and Trademark Office indicating action on this application.
2. Kindly advise the undersigned of the present status of this application.


SIGNATURE OF PRACTITIONER

Jeanette S. Harms
Reg. No. 33,834
BEVER, HOFFMAN & HARMS, LLP

Tel. No.: (408) 451-5907
Fax No.: (408) 451-5908
Customer No: 29477